

3D technology for Advanced Medical Devices Applications

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**IMAPS MEDICAL WORKSHOP
DECEMBER 4 & 5, 2012**



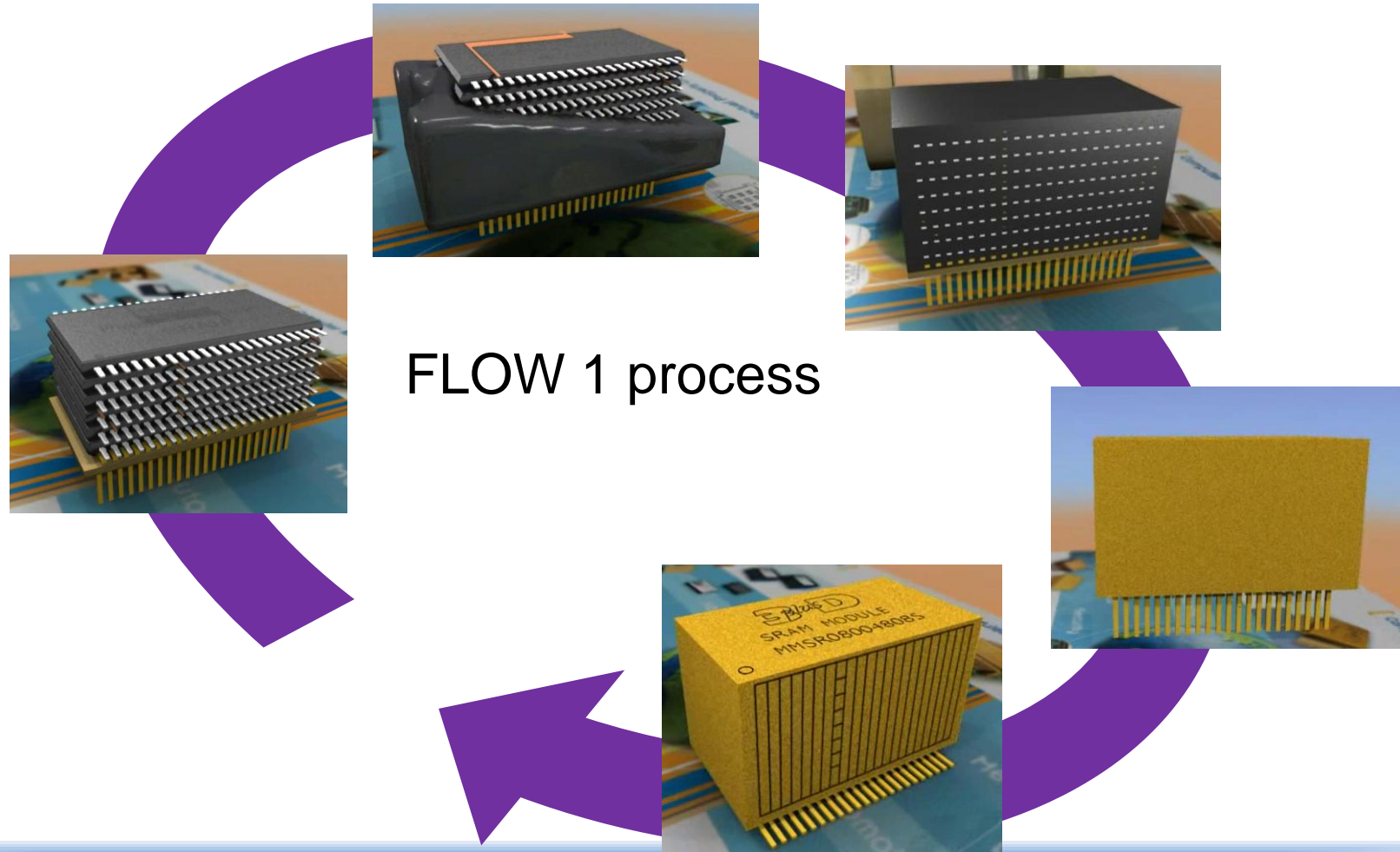
3D Plus
408, rue Hélène Boucher – ZI
Buc Cedex – France
Phone: +33 (0)1 30 83 26 50
www.3d-plus.com

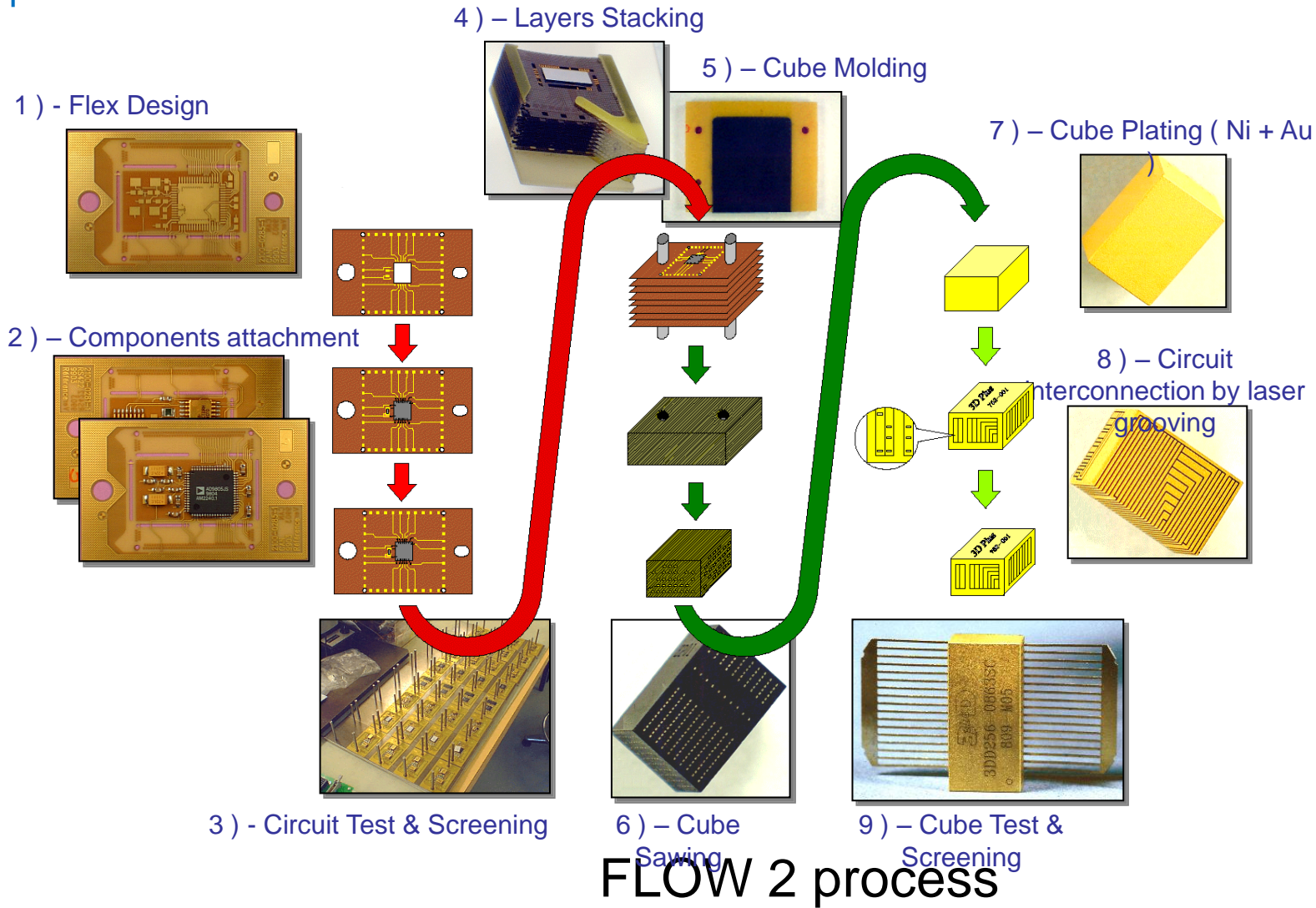
- Introduction
- Technology of the Stacking of Rebuilt Wafers
- Medical Applications
- Conclusions

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- Spin off from Thales (1996)
- From September 2011, 3D-Plus is a 100% subsidiary of HEICO company
- Strong R&D from the 3D Plus launching
- Active patenting policy
- Space certifications from CNES, ESA, NASA, JPL, JAXA, CAST etc...
- ISO 9001 from 2003
- Exportation: 90%
- Workforce : 110
- R&D : 11 including 5 PhD

- 3D-Plus is leader in space 3D memories stacking



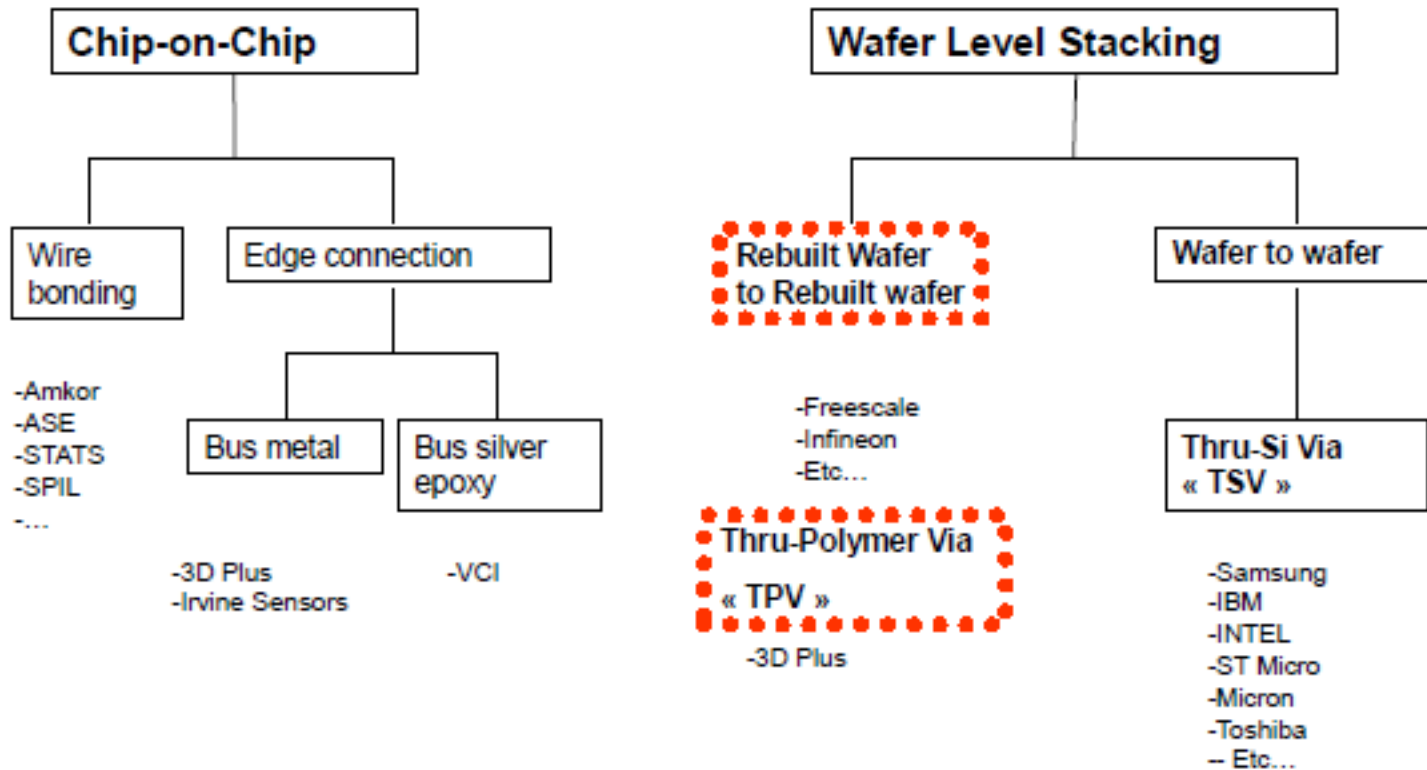




FLOW 2 process: Xray picture

- Introduction
- Technology of the Stacking of Rebuilt Wafers
- Medical Applications
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3D Existing Packaging Technology



Limits of Wafer to Wafer with TSV

- **Non multi sourcing wafers**
- **Need for smallest possible Via (2 μ m \emptyset , leads to a thickness of 20 μ m or less \rightarrow Yield of these filled via is low (redundancy is needed))**
- **Difficulties with SiP, since dies of different sizes**
- **TSV stresses (keep out zone between 20 to 200 μ m)**
- **Unfortunately impossible to have 100% good wafer \rightarrow very low global yield**

WDoD TM(1) initial criteria

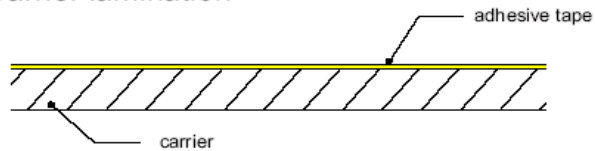
- **Use of multi sourcing wafers**
- **Stacking of 10 levels per mm, now**
- **20 levels/mm in development**
- **Size: 100µm around the larger Die**
- **Stacking of Known Good Rebuilt Wafer (KGRW)**
- **Possibility to stack Known Good Burn-In Rebuilt Wafer**
- **Parallel processing/Panelization from A to Z**

(1) Wirefree Die on Die – Trade Mark from 3D Plus

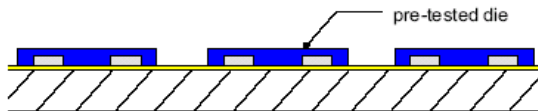


FLOW 3 "WDoD"

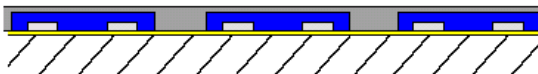
1 - Carrier lamination



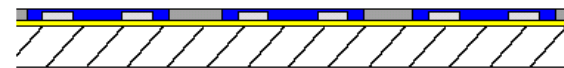
2 - Pick, Flip and place / Die on tape



3 - Compression Molding / Panel encapsulation



4 - Grinding (optional)

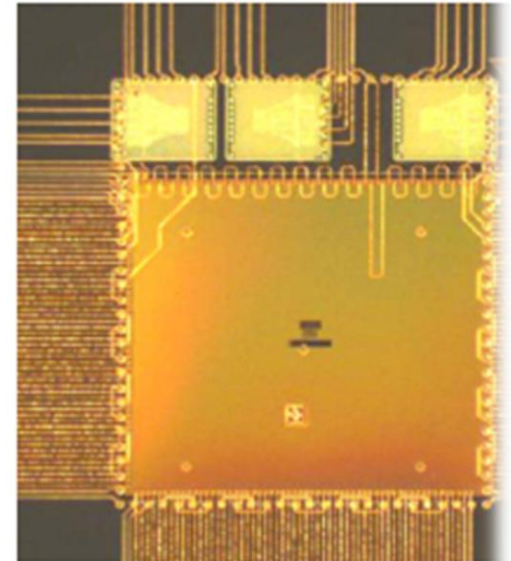
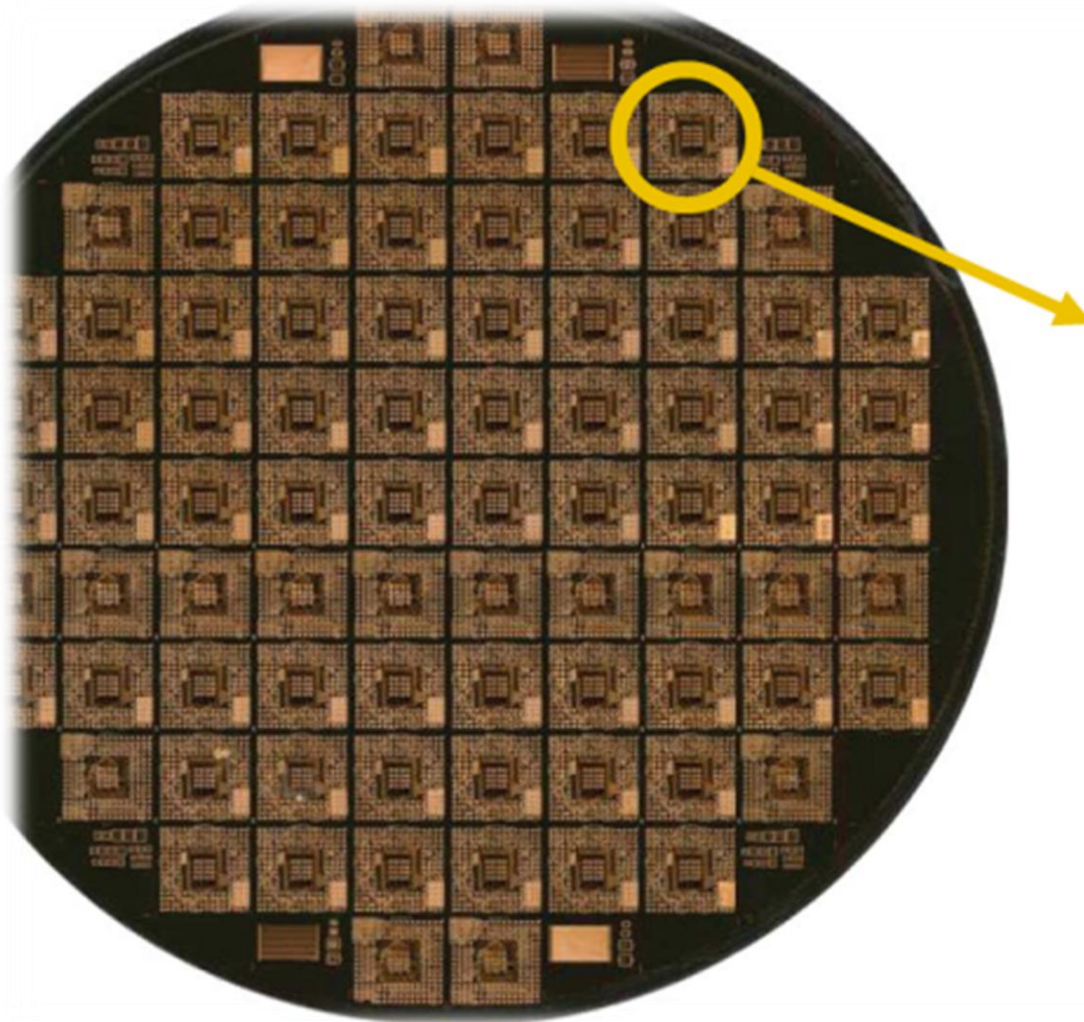


5 - De-taping



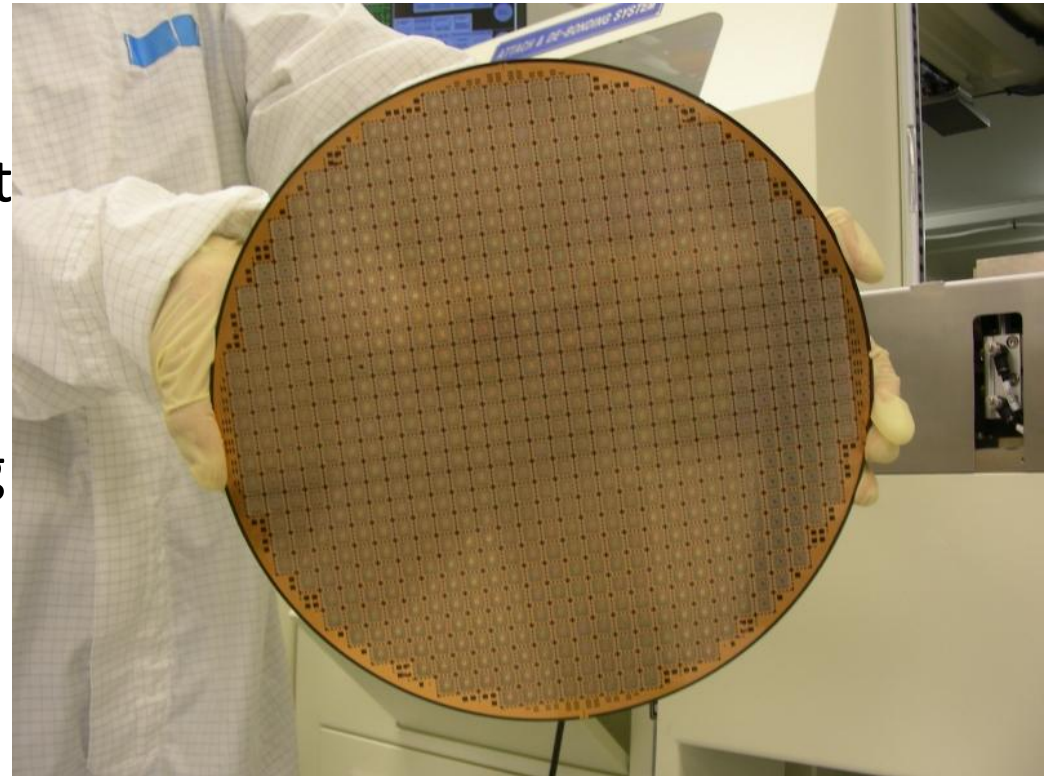
6 - Redistribution layer "RDL"





Redistributed Chip Package

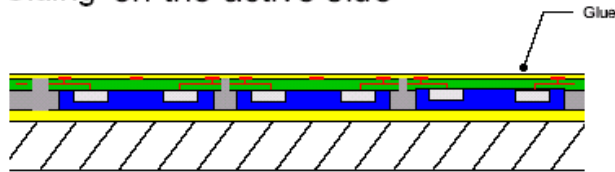
- Ultra Low k Compatible
- Good Thermal Management
- No package substrate
- No wire bond / bumps
- Large Area Batch Processing
- Single Chip or Multi Chip
- Improved Integration
- 3-D IC Enabling
- Embedded Passives, Antennas, MEMS



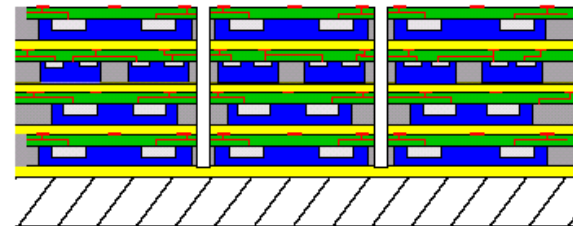
300 mm round panel
9 x 9 mm packages
258 IO, 0.5 mm pitch
716 packages/panel
2 layer build-up

FLOW 3 "WDoD"

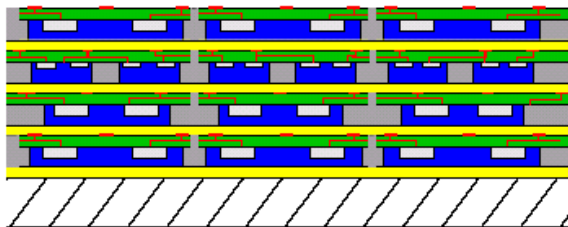
7 - Gluing on the active side



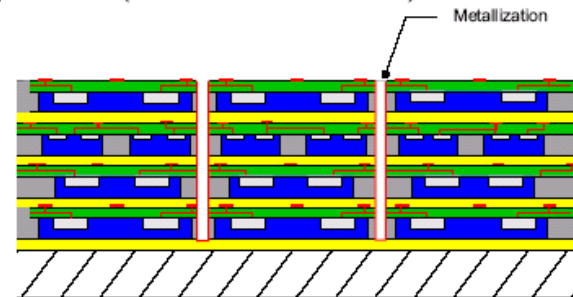
9 - Dicing of the rebuilt and stacked wafers



8 - Stacking of the "Known Good Rebuilt Wafer"



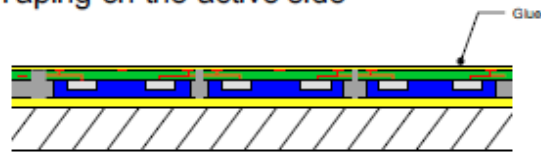
10 - Dicing street edges plating parallel process (electroless Ni + Au)



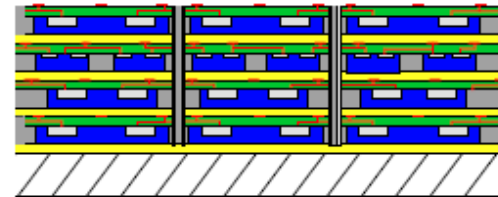


FLOW 3 "WDoD" with TPV

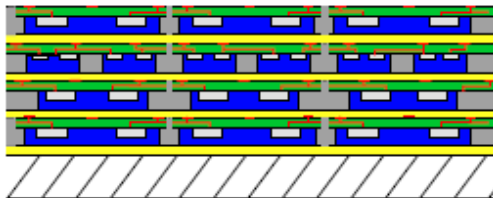
7 - Taping on the active side



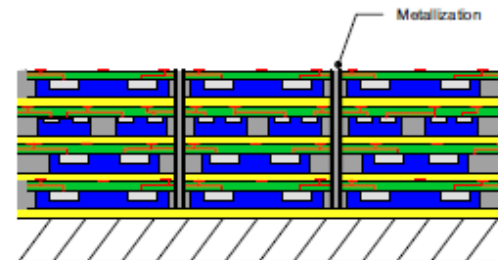
9' - Thru - Polymer - Via "TPV"



8 - Stacking of the "Known Good Rebuilt Wafer"



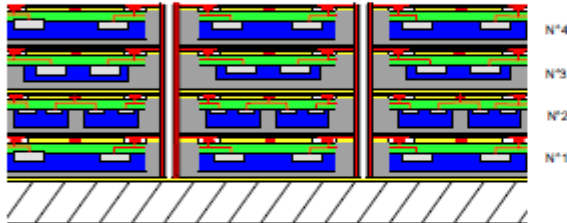
10' - Plating - "TPV"



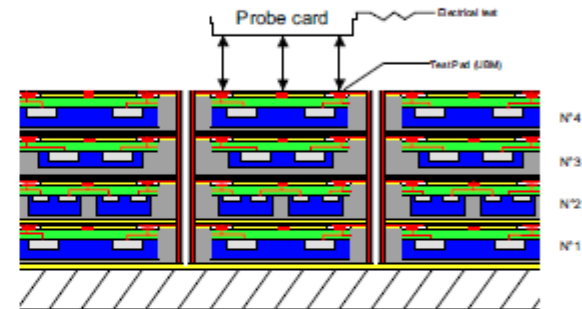


FLOW 3 "WDoD" with TPV

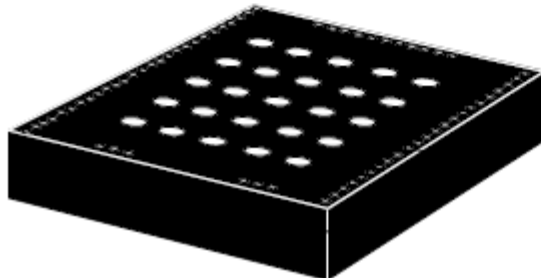
11' - Dicing of the rebuilt and stacked wafers



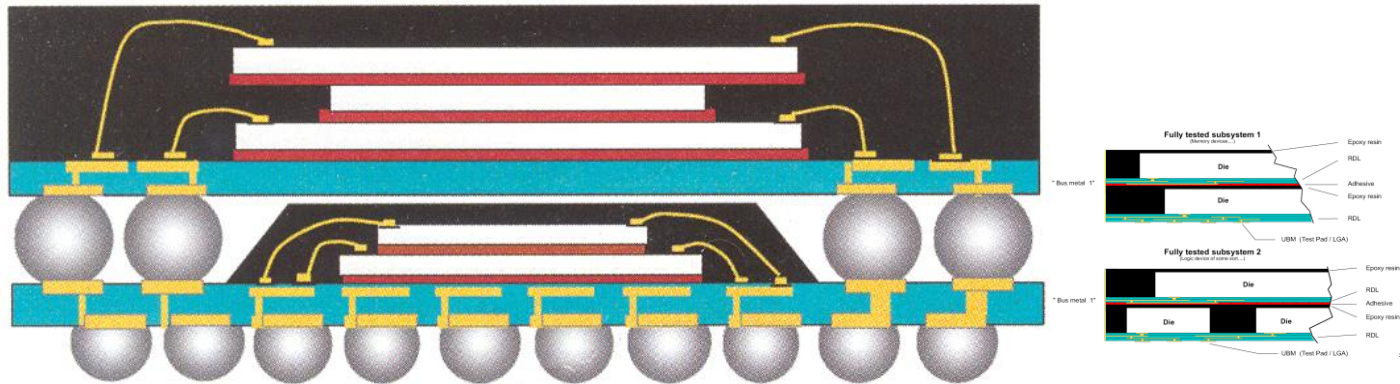
12' - Electrical test at the wafer level
(Before singulation)



13 - Singulation



3200-2607-1



PoP and WDoD package relative dimensions



FLOW 3 " WDoD"

OPTION 2
(SiP/PoP with burn-in Subsystems)

7" - Electroless Ni/Au "UBM" of the subsystem
On 2 stacked Rebuilt Wafers



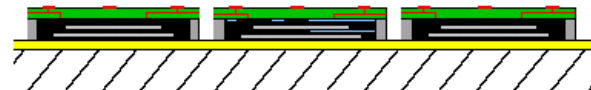
10" - Electrical tests / Burned-in
On 2 stacked Rebuilt Wafers



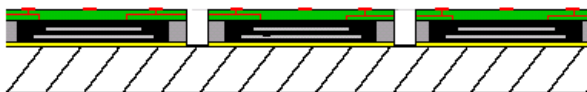
8" - Taping



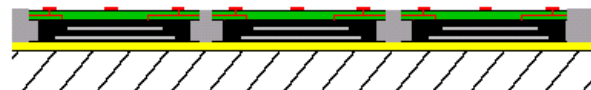
11" - Pick, Flip and place / Known Good Rebuilt
Subsystem on tape



9" - Dicing

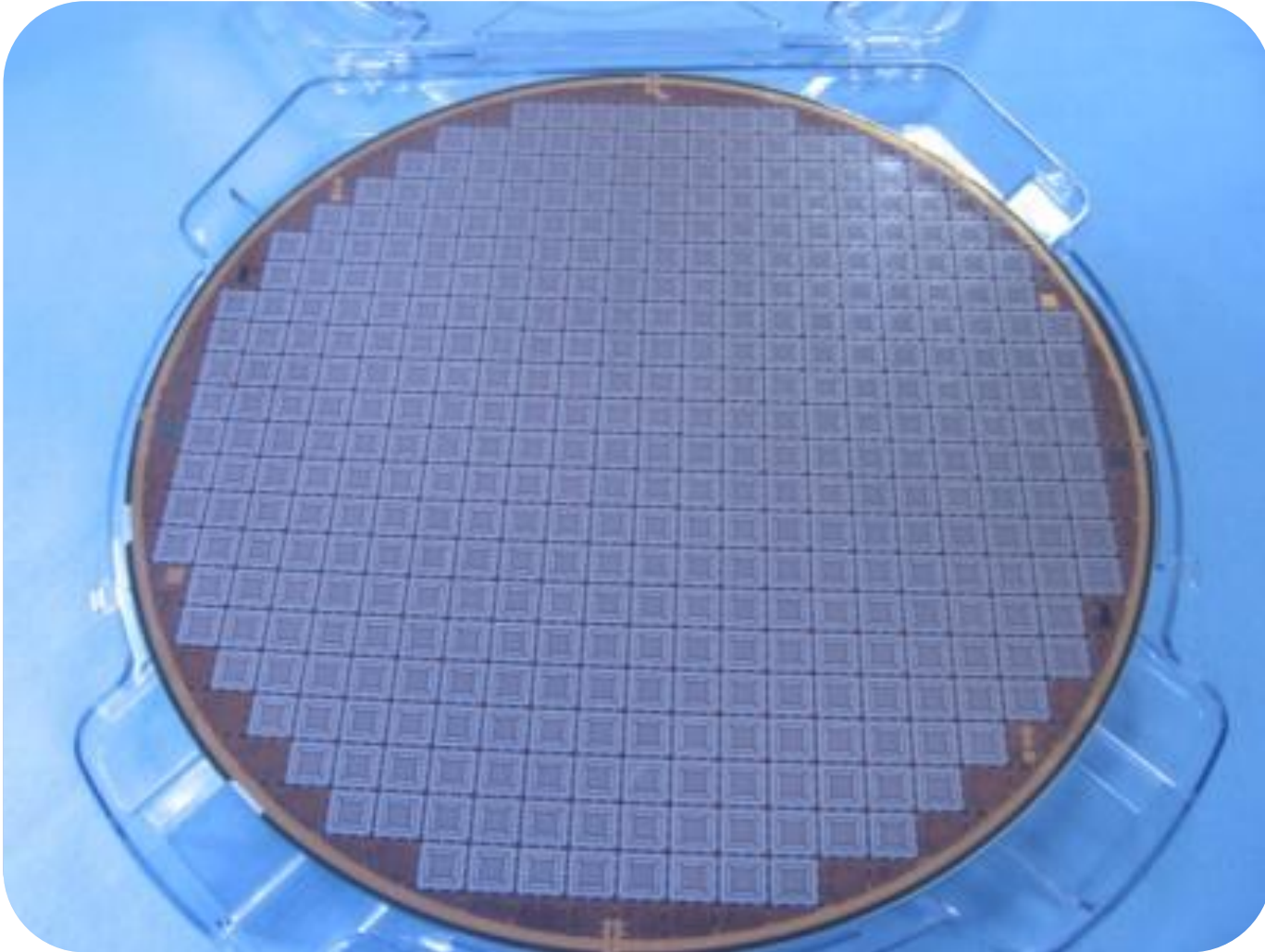


12" - Compression Molding / Curing
(Known Good Subsystem Rebuilt Wafer)



Steps 7 to 12 : Depending on the electrical tests coverage and / or the burn-in

Technology of the Stacking of Rebuilt Wafers



COMPARISON BETWEEN WAFER LEVEL PACKAGE WITH TSV, WITHOUT TSV AND PoP TECHNOLOGIES

	PoP	WAFER LEVEL PACKAGE	
		Wafer to Wafer with TSV	Rebuilt Wafer to Rebuilt Wafer without TSV
Stacking of different size of the die	Best	Poor	Best
More than 1 Die/Level	Poor	Poor	Best
Sourcing flexibility	Best	Poor	Best
Test and / or burned-in before stacking	Best	Poor	Best
Package size	OK	Best	Good
Package height	OK	Best	Good
Cost	Best	Poor	OK

Best
 Good
 OK
 Poor

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MEDICAL APPLICATIONS:

- **Micro camera for Endoscopy (1,5 x 1,5 mm)**
- **Hearing aids**
- **Modules for Pacemaker, Neuro stimulator**
- **Module for 40 silicon capacitors on 20 levels**
- **US sensor**
- **X Ray sensor**

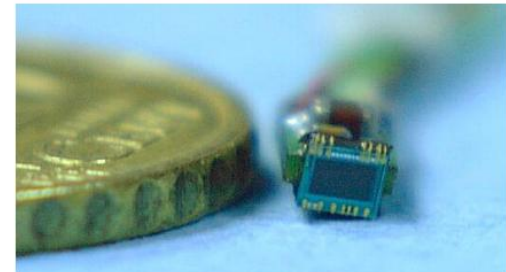
Color CMOS Micro Camera Head SMMC13039

General Description:

The new **3D Plus** Micro Camera is a highly miniaturized, light weight, high performance and easy-to-use colour CMOS Camera.

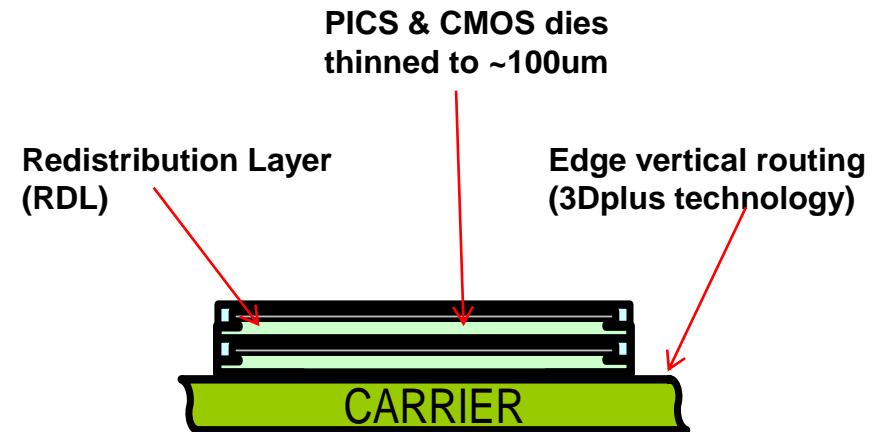
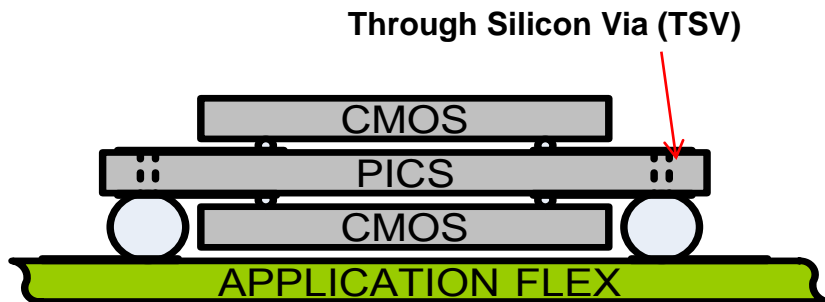
It embeds a CMOS digital sensor with transceivers and decoupling capacitors. The sensor is a 1/13 inch CMOS digital image sensor with an active array of 648 x 488 pixels. It includes sophisticated camera functions such as auto exposure control, auto white balance, black level control, flicker detection and avoidance and defect correction. The decoupling capacitors and transceivers grant it to drive a long length cable directly from the chip. It is designed for low light performance and programmable through a simple serial interface.

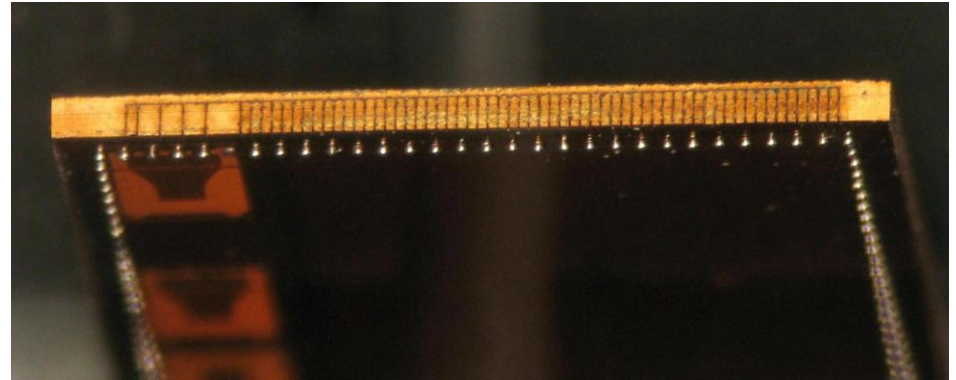
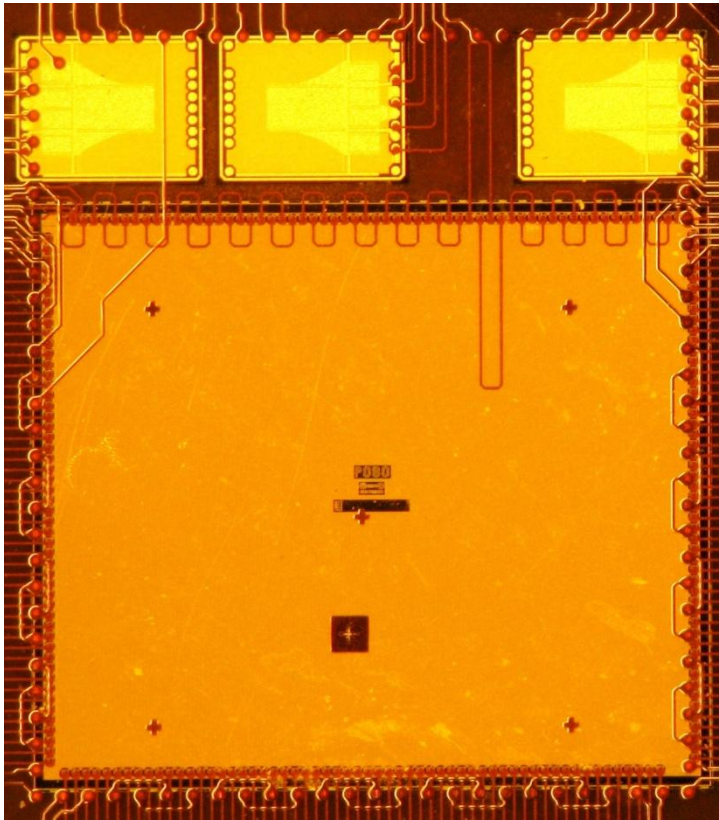
The new **3D Plus** Micro Camera fits very well applications requiring long length cable driving capabilities such as endoscopes. The innovative design makes them also suitable for applications in the area of robotics, assembly and mounting devices or manipulators.



HEARING AIDS

- Going further than flip-chip – 3D SiP integration for hearing aids
 - Through Silicon Vias (TSV)
 - Edge Vertical Routing (Based on 3DPlus technology)



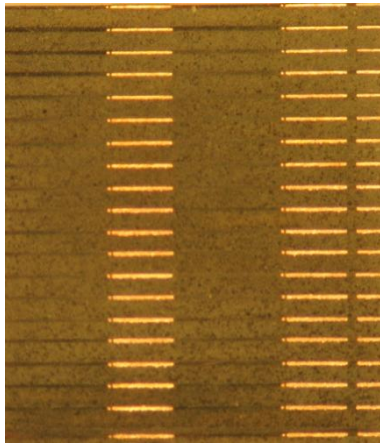
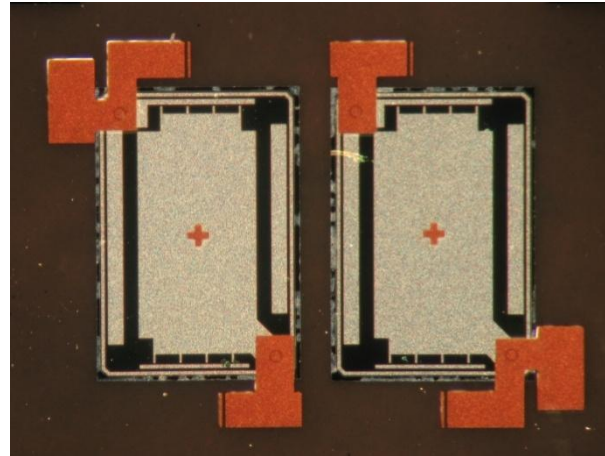
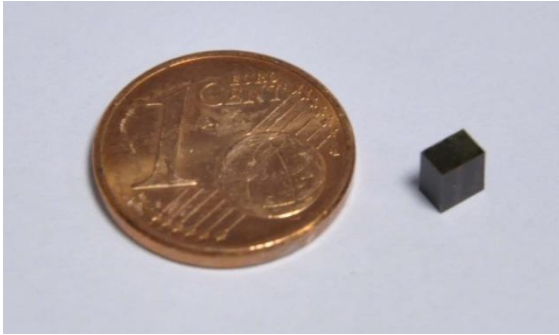


Demonstrator with PICS and DS die for qualification with one major pacemaker manufacturer



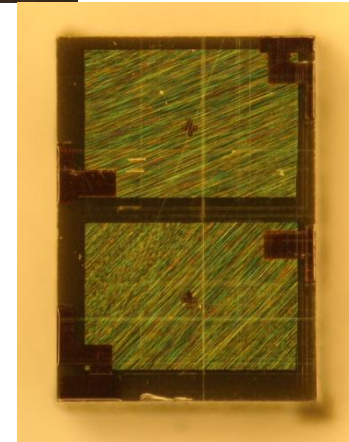
Neurostimulator:

- Diameter 3 mm
- 1 MEMS
- 3 ASICs
- 1 analogic die
- 2 capacitors
- 1 antenna



PICS capacitors stack

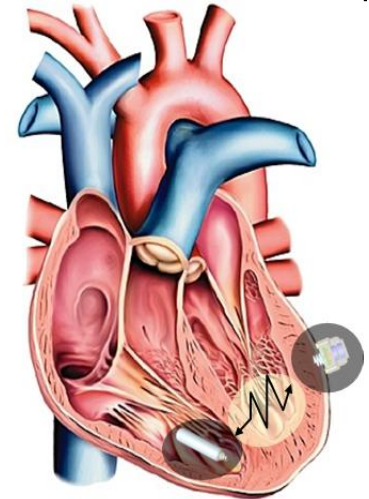
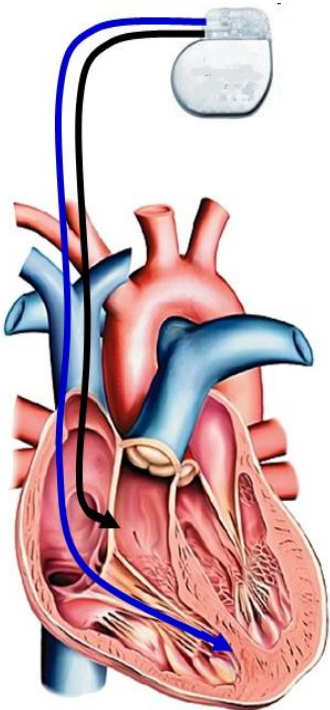
-20 levels of capacitors pairs



LEADLESS PACEMAKER DEMONSTRATOR IN FP7 PROGRAM:

Objectives

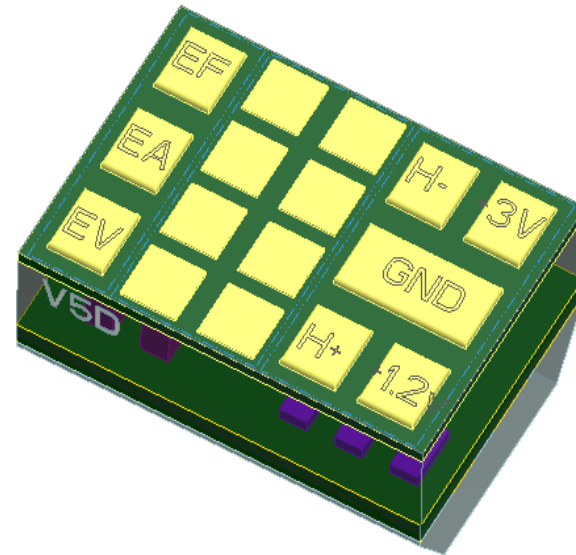
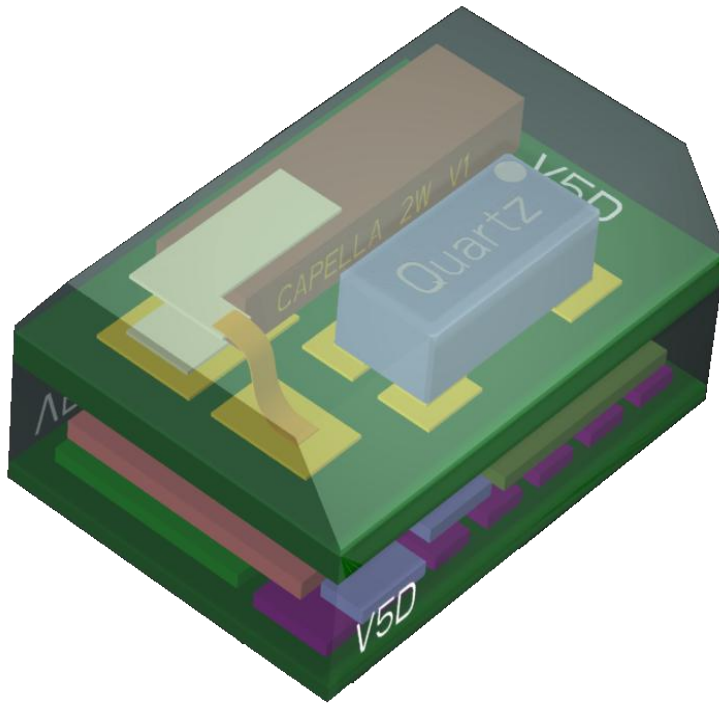
- Realization of a “leadless” pacemaker demonstrator
 - Reduce the size by x 16 (8 cc → 0.5 cc)
 - Eliminate the connecting leads

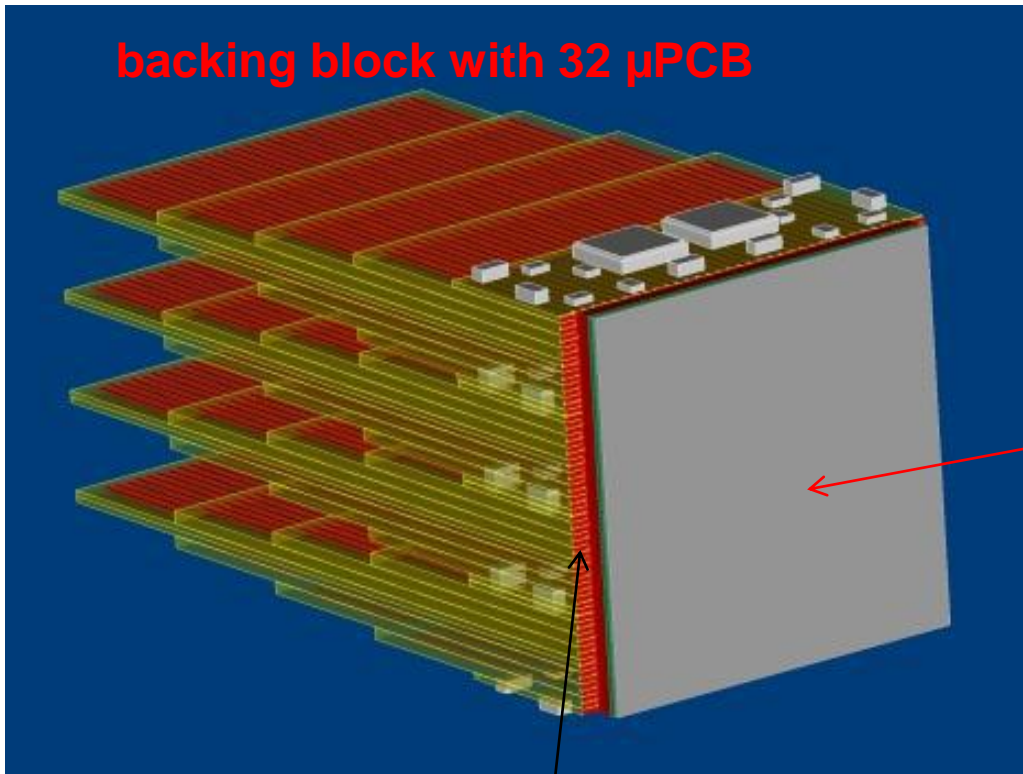


- **Energy scavenger :
heart contraction
movement → electrical
energy**
- **Low Voltage ASIC**
- **High Voltage ASIC**
- **High density isolated
capacitors : power
storage**
- **Assembly of
electronic in 3D
stacking**



- **Dimensions : 2.3 x 5.2 x 7.3 mm**





Ultrasonic probes

Applications

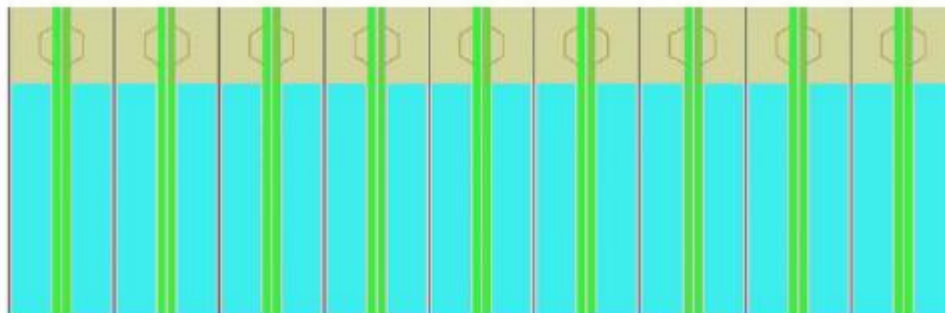
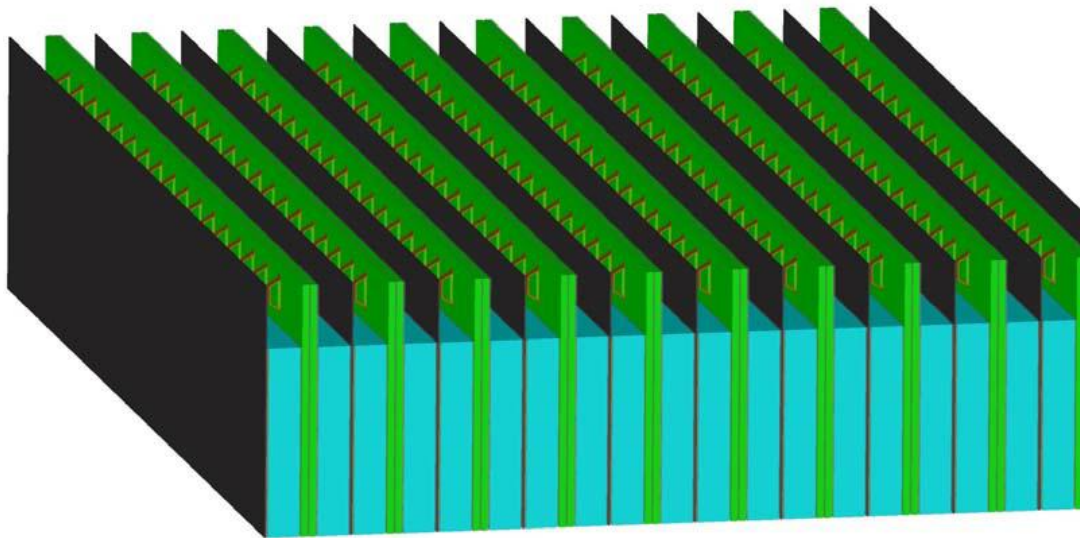
- Real time 3D ultrasonic imaging

Transducer array

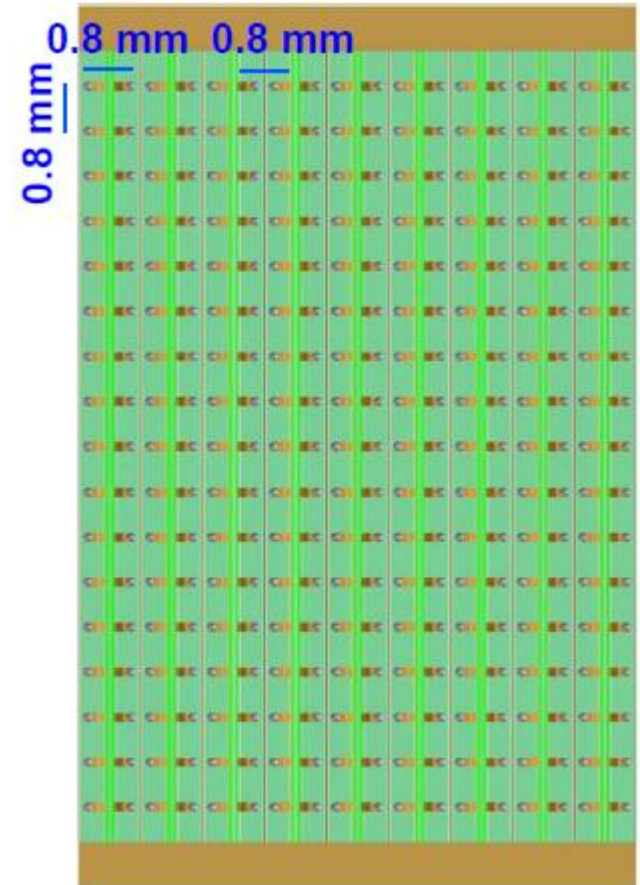
- 64x64 elements
- **Array size : $\approx 28 \times 28 \text{mm}$**

Interposer between transducer array and backing block

XRAY CdTe SENSOR FOR MEDICAL IMAGERY



side view

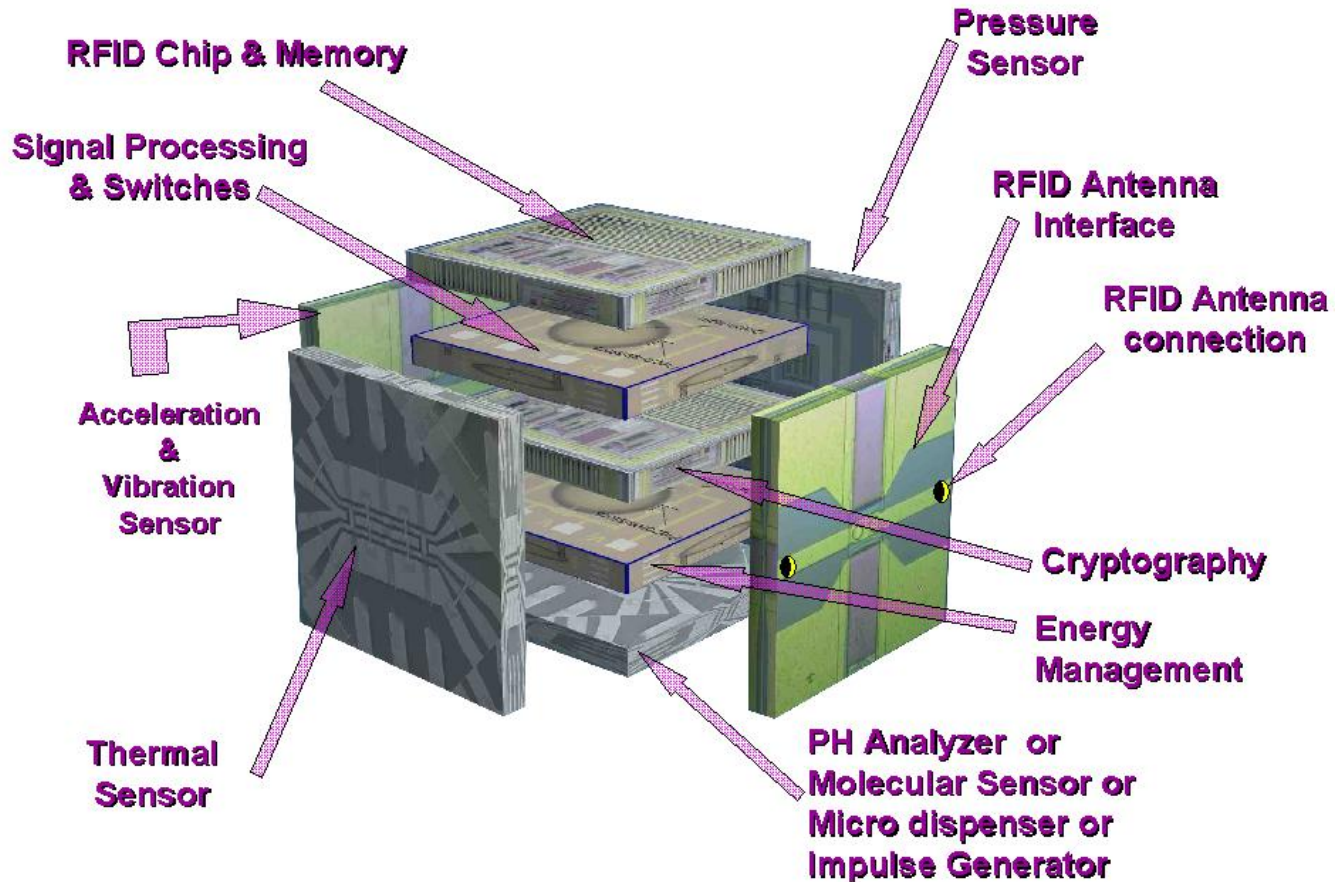


top view

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- Medical Applications
- **Conclusions**

- **Proof of Concept – completed (2002-2005)**
 - **European funding (25 M\$) with CEA/LETI, AXALTO, ST Microelectronics, 3D PLUS, ...**
- **Process Development & Optimization of WDoD (from 2006 up to Feb 2009) with NXP/Philips semiconductor**
- **From Feb 2009 Prototyping with the RCP Process from Freescale/Phoenix**
- **From Feb 2011 Prototyping with the e-WLB Process from Nanium (ex Quimonda) /Porto**
- **Functional Prototypes with DR3/JEDEC Qualifications (first Semester of 2013)**
- **Manufacturing Line for Prototypes and Small Volume Qualification (first Semester of 2013)**

- **Miniaturization for Consumer, Medical and security domains demands very high interconnection densities and low costs .
Reconsidering former experiences: Hybrids, Multichip Modules, Wafer Scale Integration (20 years ago), PoP instead of PiP; we learned that the yield constituted an important part of the production costs.**
- **The WDoD process only allows to stack Known Good Rebuilt Wafers .**
- **Several applications in the medical have been presented.**
- **This important densification of 10, soon 20 levels per mm, allows to launch extremely ambitious applications in the field of System in Package**



Ultra Dense 3-D Micro system with WDoD

Thank you for your attention
www.3d-plus.com